



*Probing equipment and accessories  
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## Signatone CheckMate Probe Station

The Signatone CheckMate is an ultra-stable 8" / 12" analytical probe station with coarse and fine wafer stage movement to provide fast wafer movement as well as submicron resolution. Five versions of CheckMate probe station are available. The CM-100 has manual control of both wafer and microscope stages and is pre-wired for e in-the-field upgrade to motorized control. The CM-200 has joystick controlled motorized movement of both the microscope and wafer stage. The CM-300 has a joystick unit with precision dials to control both the microscope and wafer stages. The CM-400 uses a PC an programmable capability for the microscope and up to four CAP Pr (computer aided probes) using the Signatone Solutions Windows b Software. The CM 500 has automated wafer stepping capability an available with an optional cassette-to-cassette wafer loading syste

The CheckMate series probe stations are available with Signatone' local dry chamber option. This option provides a local environment chamber around the wafer stage to provide:

- Elimination of moisture or frost build-up when using a cold chuck (-65°C to +200°C)
- A dark environment for making light sensitive measuremen
- EMI Protection, i.e., shielding from electromagnetic and electrostatic interference, allowing low current measureme using Signatone's Tripak triaxial technology. The Tripak package provides measurement capability down to the noise floor capability of instruments such as the HP4156A param analyzer ( 1 fA).

Whether your need is for failure analysis, product engineering, design/debug, or any of the many probing applications that Signat addresses, the CheckMate Probe Station can be configured to me your needs with accuracy, stability, ease-of-use, and a wide assort of options and capabilities.

CM100 - Manual 8" or 12" probe station, 2" X-Y microscope movement, large platen accepts up to 10 vacuum based micropositioners

CM200 - 8" or 12" probe station with manual and motorized joystick control of wafer chuck and microscope movement

CM300 - 8" or 12" probe station with motorized joystick cont and precision DIAL control (3 dials) of X-Y chuck movemen Y-Z microscope movement, and X-Y-Z movement of up to CAP (Computer Aided Probes).

CM400 - 8" or 12" probe station with motorized joystick cont and precision DIAL control (3 dials) of X-Y chuck movemen

and precision DIAL control (3 dials) of X-Y chuck movement, Y-Z microscope movement, and X-Y-Z movement of up to CAP (Computer Aided Probes) with Signatone Solutions Windows Software and a PC providing programmable control of the microscope (X-Y-Z) and up to four CAP probes.

CM500 - 8" or 12" Autostepping probe station with motorized joystick control and precision DIAL control (3 dials) of X-Y chuck movement, X-Y-Z microscope movement, and X-Y-Z movement of up to 4 CAP (Computer Aided Probes) with Signatone Solutions Windows Software and a PC providing program control of the wafer stage, the microscope (X-Y-Z) and up to four CAP probes.

**Request for information**

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